

Figure 1

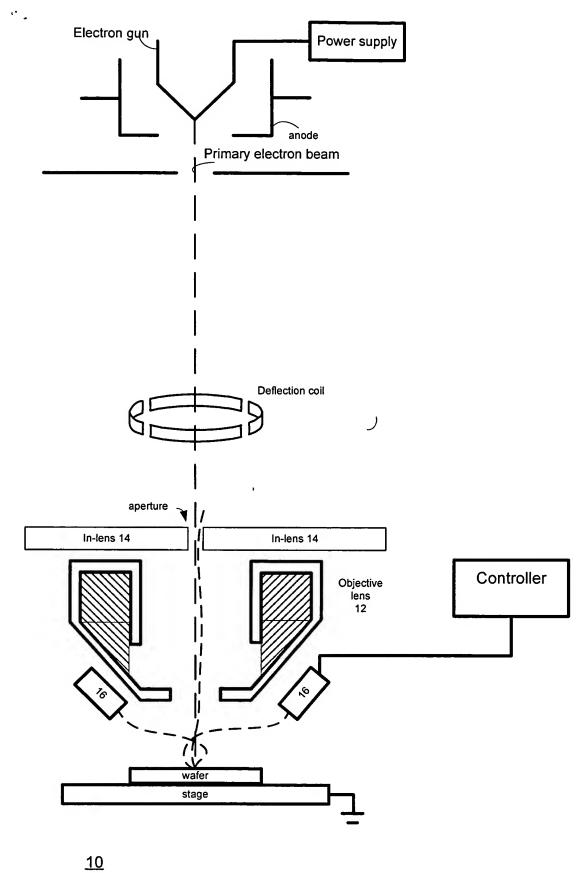
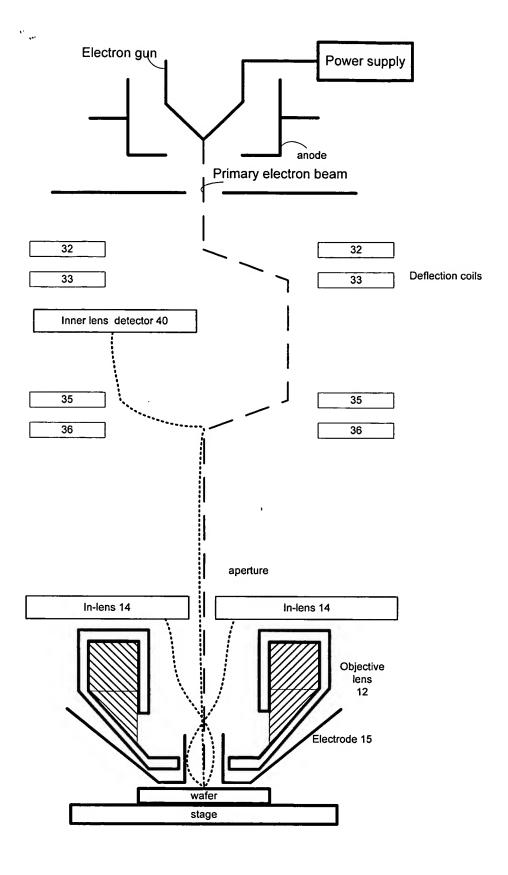


Figure 2a



<u>10'</u>

Figure 2b

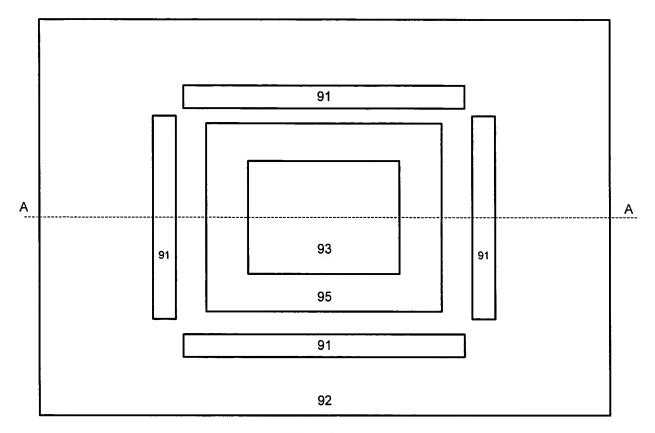


Figure 3a

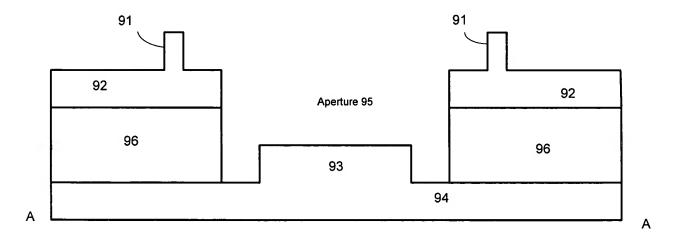


Figure 3b

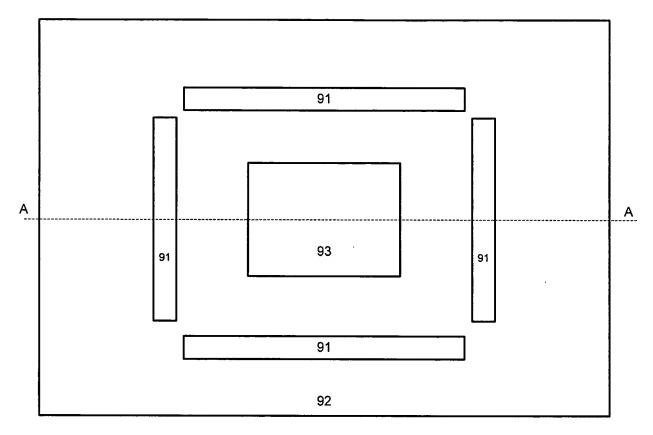


Figure 4a

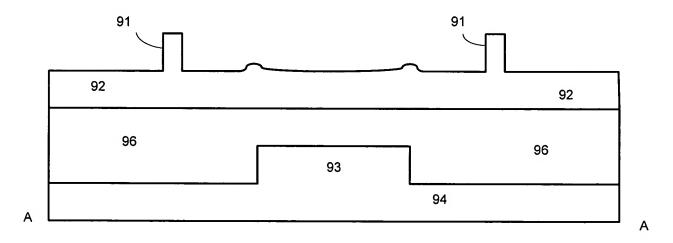


Figure 4b

directing a primary electron beam to interact with an inspected object. The inspected object includes a first feature formed on a first layer of the inspected object and a second feature formed on a second layer of the object, wherein the second feature is buried under the first layer and wherein the second feature affects a shape of an area of the first layer 202

detecting electrons reflected or scattered from the inspected objects, and especially from the area.

204

receiving detection signals from at least one detector and determining overlay errors 206

<u>200</u>

Figure 5

directing a primary electron beam to interact with a first feature and a second feature of an inspected object. The first feature is formed on a first layer of the inspected object and the second feature formed on a second layer of the object. The second feature is buried under the first layer.

212

directing electrons reflected or scattered from the first and second features towards at least one detector

214

receiving detection signals from at least one detector and determining overlay errors 216

210

Figure 6